

Istituto Nazionale di Fisica Nucleare SEZIONE DI TORINO



# Latest results on RSD2 performances, a lab update

18th Trento Workshop on Advanced Silicon Radiation Detectors LUCA MENZIO UNIVERSITÀ DI TORINO-INFN UFSD group – LISS

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#### Outline

- Introduction
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  - Resistive Silicon Detectors
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- Experimental setup
- Analysis and results
  - Spatial Resolution
  - Temporal Resolution
- Conclusions









#### Motivations

Need for spatial information in future HEP experiments<sup>(1)</sup>

Facility:	FCC-ee	ILC	CLIC
$\sigma_{hit\ pos}\ [\mu{ m m}]$	$\sim 5$	< 3	< 3
Thickness $[\mu m \text{ of } Si]$	$\sim 100$	$\sim 100$	$\sim 100$
Hit rate $[10^6/s/cm^2]$	$\sim 20$	$\sim 0.2$	$\sim 1$
Power dissipation $[W/cm^2]$	0.1 - 0.2	0.1	0.1

Plus timing information, 5-25 ps depending on the facility.

Traditional sensors have difficulties in fulfilling these tasks:

- 5  $\mu$ m obtainable with 25x25  $\mu$ m<sup>2</sup>, <u>but</u> the number of channels is too high
- Better resolutions are possible with charge sharing due to external magnetic field, <u>but</u> sensors become too thick

A new solution is needed





### **Resistive Silicon Detectors**

Change in silicon sensors paradigm: Resistive Silicon Detector (RSD)



- Contained channels number
- Thin sensors
- + 100 % intrinsic fill factor!
- Low power consumption
- Low material budget





#### **Resistive Silicon Detectors**

RSD can be AC or DC coupled to their readout







# (AC-)RSD Principles of Operation

e-h pairs are produced by the impinging particle in the sensor volume



- Charge is induced in the n+ layer (1 ns)
- Nearby AC pads see a fast signal thanks to capacitive coupling

Signal sharing

• Charges in the n+ flow to ground

In normal pixel detectors 
$$\sigma_{\chi} = k \frac{pitch}{\sqrt{12}}$$
 with k~0.5 - 1

(AC-)RSD have

- $\sigma_x \ll \text{pitch}$
- Time resolution proper of thin LGADs





#### Standard Silicon Detector vs RSD



**Standard Silicon Detector** 

**Resistive Silicon Detector** 

++

Pixel size ~ 250 x 250 μm<sup>2</sup>

~ 50

μm

**Resistive implant** 

Gain implant





### **Devices Under Test**

From the RSD 1 production, we learned that for optimal results:

- Not too many pads should be involved S/N ratio worsens
- The number of pads involved should be the same over the sensor surface
- Careful tuning of the pads capacitance less metal on the pads

Ideas implemented in RSD 2 and various electrodes shapes implemented







#### **RSD 2 DUTs in Photos**











# RSD 2 by FBK

#### RSD 2 consists of 15 wafers with different characteristics.

Wafer #	Type	Carbon	n <sup>+</sup> dose	p gain dose
1	Si-Si 55 µm	N	А	0.96
2	Si-Si 55 µm	Ν	A	0.96
3	Si-Si 55 µm	N	A	0.98
4	Si-Si 55 µm	Ν	А	1
5	Si-Si 55 µm	N	A	1
6	Epi 45 $\mu m$	N	В	1
7	Si-Si 55 µm	N	В	0.98
8	Epi 45 $\mu m$	Ν	В	0.96
9	Epi 45 $\mu m$	N	В	0.96
10	Epi 45 $\mu m$	Y (1)	В	0.96
11	Epi 45 $\mu m$	N	С	0.96
12	Epi 45 $\mu m$	Y(0.8)	C	0.96
13	Si-Si 55 µm	Ν	C	0.98
14	Epi 45 $\mu m$	N	C	0.98
15	Si-Si 55 µm	N	С	0.94

• n<sup>+</sup> dose (A < B < C)

• Gain

0

- Wafer type (Epitaxial and Floating Zone)
- Pad capacitance

Electrostatics measurements were performed on all wafers<sup>(2)</sup>

On a selection of these

• Fine TCT inspection

Test beam @ DESY

This presentation

F. Siviero (next talk)







### **Experimental Setup**

All measurements were performed in the Torino Laboratory for Innovative Silicon Sensors (LISS)



The setup consists of a TCT by Particulars equipped with a

- IR laser simulating the passage of 1-3 MIP(s)
- $\circ$  Laser spot size of ~10  $\mu m$  FWHM



A precise x-y stepper provides reference positions of the laser on the sensor surface

 $\circ$   $\sigma_{step} \sim 2 \ \mu m$ 

Multiple signals (50-100) are produced and recorded at each point

The whole active area is scanned with 10-20  $\mu m$  steps



#### **Experimental Setup**

All sensors were bonded on a 16-ch Fermilab board

- Double-stage amplifiers
- RMS noise @roomT ~ 2-3 mV

The output signals are read out employing a 5 GS/s 16-ch digitizer

An output rootfile containing positions and sampled waveforms is produced and undergoes

- "standard" c++ analysis<sup>3</sup>
- Machine Learning-based approach<sup>4,5</sup>











#### **Resolutions parametrization**

#### Space

$$\sigma_{pos}^2 = \sigma_{jitter}^2 + \sigma_{rec}^2 + \sigma_{setup}^2 + \sigma_{sensor}^2$$

- $\sigma_{jitter}^2$  due to the variation in the signal amplitude caused by the electronic noise ~ noise/amplitude
  - $\sigma^{z}_{rec}$  accuracy of the reconstruction method
- $\sigma^2_{setup}$  related to eventual variations in the signal sharing due to the experimental setup (i.e. amplifiers)
- $\sigma^2_{sensor}$  all sensor imperfections that could contribute to differences in signal sharing



$$\sigma_{time}^2 = \sigma_{jitter}^2 + \sigma_{Landau}^2 + \sigma_{delay}^2$$

- $\sigma_{jitter}^2$  similar as before, ~ noise/(dV/dt)
- $\sigma^2_{Landau}$  non-uniform ionization contributes with ~30 ps in 50  $\mu$ m thick sensors
- $\sigma^2_{delay}$  propagation time from the impact point to the read-out pad. It is correlated to the precision of the hit position reconstruction





### **Space Reconstruction**

Considering a sensor with 450  $\mu$ m pitch

$$\sigma_{pos} \sim \frac{pitch}{\sqrt{12}} \sim 130 \ \mu m$$

In RSD 2, spatial coordinates (x-y) are reconstructed with the method of the "charge asymmetry"

$$x_{i} = x_{center} + k_{x} \frac{pitch}{2} \frac{A_{3} + A_{4} - (A_{1} + A_{2})}{\sum A_{j}}$$
$$y_{i} = y_{center} + k_{y} \frac{pitch}{2} \frac{A_{1} + A_{3} - (A_{2} + A_{4})}{\sum A_{j}}$$

We employed the amplitude A







#### **Correction Matrix**

A correction matrix is generated with the highest amplitudes dataset.

The migration of the data is then applied to all datasets, bringing the average point position to (almost) overlap with the true one.

This correction drastically improves the accuracy of the reconstruction method, especially in cases of low amplitudes





After correction

#### **Space Reconstruction**

After the correction with the migration matrix, the results improve

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**Before correction** The same correction matrix is applied to the lower-gain datasets.

> ~ 15 µm









Different wafers can be studied with a fixed geometry – 450  $\mu$ m pitch



Wafer $\#$	Type	Carbon	$n^+$ dose	p gain dose
3	Si-Si 55 µm	Ν	A	0.98
7	Si-Si 55 µm	Ν	В	0.98
15	Si-Si 55 $\mu m$	Ν	$\mathbf{C}$	0.94

The different wafers behave in the same way

The jitter term depends on the amplitude as 1/A.

Since the data agrees quite well with the 1/A behavior, the resolution is dominated by the jitter term





The smallest DUT - 200 x 340  $\mu m^2$ 



Wafer $\#$	Type	Carbon	$n^+$ dose	p gain dose
3	Si-Si 55 µm	Ν	A	0.98
7	Si-Si 55 $\mu m$	Ν	В	0.98
15	Si-Si 55 $\mu m$	N	$\mathbf{C}$	0.94

W3 200 um
W3 340 um
W15 200um
W15 340 um

For the smallest pitch, the wafer with the highest n+ resistivity (W3) achieves the best resolution.

This is expected since at lower resistivities the signal is spread on too many electrodes





#### Largest DUT - 1.3 mm pitch

Luca Menzio – INFN Torino



Wafer $\#$	Type	Carbon	$n^+$ dose	p gain dose
3	Si-Si 55 $\mu m$	Ν	A	0.98
7	Si-Si 55 $\mu m$	Ν	В	0.98
15	Si-Si 55 $\mu m$	Ν	$\mathbf{C}$	0.94

Resistivity seems to play an important role also in big sensors

Lower resistivity helps the signal travel longer distances

W7 measurements are currently undergoing





#### **Time Reconstruction**

Each pad signal is an estimator of the time coordinate, weighted on its amplitude

 $t_i = \frac{\sum_j^4 t_j^{rec} A_j^2}{\sum_j^4 A_j^2}$ 

Where  $t_j^{rec} = t_j^{meas} + t_j^{delay}$ , the delay is computed from the correction matrix and  $t_j^{meas}$  corresponds to the time at the signal maximum.

To the obtained value is subtracted the trigger contribution (~ 10 ps)

In the case of TCT measurements, the Landau term is not present.







#### **Time Resolution Results**

#### Very uniform performance









#### Conclusions

RSD technology has proven to be a promising candidate as a 4D detector, combining LGADs timing and the innovative charge sharing in silicon for position reconstruction

- Position resolution is better than in standard sensors
  - The n+ layer resistivity is to be tuned on the pixel size
- Time resolution of "standard" LGADs is maintained
  - Time jitter is lower for sensors with lower resistivity due to the signals shape

Very useful information for future developments on DC-RSD

More on RSD 2 results (test beam @Desy) in the next talk



#### Thank you!





### Special Thanks to

We kindly acknowledge the following funding agencies and collaborations:

- INFN Gruppo V, UFSD and RSD projects
- INFN FBK agreement on sensor production (convenzione INFN-FBK)
- Horizon 2020, grant UFSD669529
- o Dipartimenti di Eccellenza, Univ. of Torino (ex L. 232/2016, art. 1, cc. 314, 337)
- Ministero della Ricerca, Italia , PRIN 2017, progetto 2017L2XKTJ 4DinSiDe
- Ministero della Ricerca, Italia, FARE, R165xr8frt\_fare
- Marta Tornago for all the nice drawings

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- 4. "First experimental results of the spatial resolution of RSD pad arrays, readout wit a 16-ch board", F. Siviero et al., arxiv.org/abs/2204.06388.
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Different wafers can be studied with a fixed geometry



Wafer $\#$	Type	Carbon	$n^+$ dose	p gain dose
3	Si-Si 55 µm	Ν	А	2.45
7	Si-Si 55 µm	Ν	В	2.45
15	Si-Si 55 µm	Ν	С	2.35





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#### Performances at a fixed amplitudes sum

